

Supplementary Information

Ga Back-Graded CuInSe₂ Thin Films for High-Performance Near-Infrared Photodetectors

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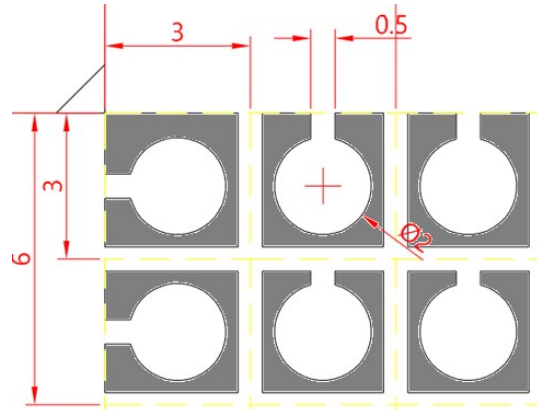


Fig. S1. Schematic layout and dimensional parameters of the Ag top electrode (dimensions in mm).

Table S1. State-of-the-art PCE values of CIGSe and CIGS solar cells.

| Device Type | Absorber | PCE (%) | Optimization Strategy | Ref. |
|-------------|------------------------|---------|---|-----------|
| CIGS/SLG | Ag-alloyed CIGS | 23.64 | Ag alloying + RbF PDT | [1] |
| CIGS/UTG | Ag-alloyed CIGS on UTG | 17.81 | Ag alloying + NaF/RbF PDT + ZnMgO | [2] |
| CIGSe/SLG | Ag-alloyed CIGSe | 18.70 | Ag alloying + Rb-In-Se capping + NaF PDT | [3] |
| CIGSe/SLG | Pure CIGSe | 13.20 | No front passivation | [4] |
| CIGSe/SLG | Pure CIGSe | 6.17 | No front passivation; inverted 1st/3rd stages | This work |

Table S2. State-of-the-art NIR photodetection performance of CISE and CIGS photodetectors.

| Material | Device Structure | λ (nm) | R (AW ⁻¹) at 0 V bias | D* (Jones) at 0 V bias | Response Time | Active area | Ref. |
|----------|-----------------------------------|----------------|-----------------------------------|------------------------|---------------|----------------------|-----------|
| CIGS | Mo/CIGS/CdS/ZnO/ITO (SLG) | 660 | 0.25 | 1.2×10^{11} | 0.05 μ s | N/A | [5] |
| CISE | ITO/HybridHTL/CISE QDs/ZnO/Ag | 1050 | 0.08 | 2.1×10^{12} | 0.64 ms | 0.78 mm ² | [6] |
| CISE | ITO/PEDOT:PSS/Mn–CISE QDs/PCBM/Ag | 1000 | 0.03 | 4.2×10^{12} | 0.76 μ s | 0.10 cm ² | [7] |
| CISE | SLG/Mo/CISE/CdS/i-ZnO/ITO/Ag | 1064 | 0.67 | 2.5×10^{12} | 0.18 ms | 3.14 mm ² | This work |

Table S3. FESEM-EDS analysis of Ref, Ga3 and Ga6 thin films from bottom (P1) to top (P5).

| Elem. | G0 (at.%) | | | | | G3 (at.%) | | | | | G6 (at.%) | | | | |
|-------|-----------|-------|-------|-------|-------|-----------|-------|-------|-------|-------|-----------|-------|-------|-------|-------|
| | P1 | P2 | P3 | P4 | P5 | P1 | P2 | P3 | P4 | P5 | P1 | P2 | P3 | P4 | P5 |
| Cu | 23.62 | 23.45 | 23.53 | 23.64 | 23.46 | 22.09 | 22.13 | 22.93 | 23.48 | 23.72 | 22.87 | 22.76 | 23.22 | 24.1 | 24.3 |
| In | 26.30 | 26.67 | 26.52 | 26.24 | 26.61 | 25.45 | 25.86 | 25.81 | 25.61 | 25.73 | 23.59 | 24.25 | 25.1 | 25.01 | 25.46 |
| Ga | 0 | 0 | 0 | 0 | 0 | 2.17 | 1.54 | 0.69 | 0.52 | 0.11 | 4.13 | 3.78 | 1.45 | 0.41 | 0.37 |
| Se | 50.08 | 49.88 | 49.95 | 50.12 | 49.93 | 50.29 | 50.47 | 50.57 | 50.39 | 50.44 | 49.41 | 49.21 | 50.23 | 50.48 | 49.87 |
| CGI | 0.898 | 0.879 | 0.887 | 0.9 | | | | | | | 0.812 | 0.875 | 0.948 | 0.941 | |
| GGI | 0.000 | 0.000 | 0.000 | 0.0 | | | | | | | 0.135 | 0.055 | 0.016 | 0.014 | |

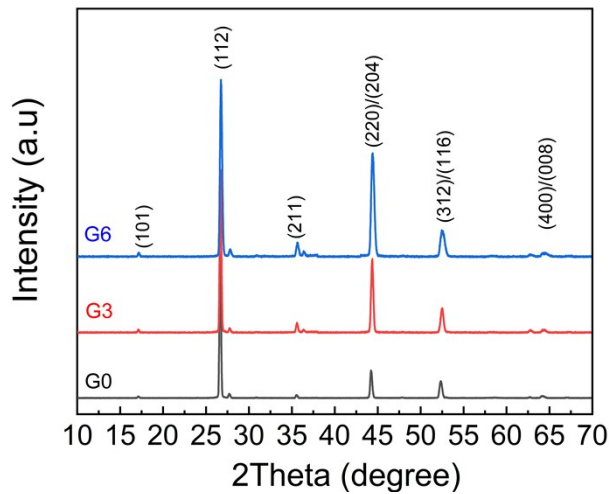


Fig. S2. XRD spectrums of CISE films G0, G3 and G6.

Table S4. XRD peak positions and FWHM analysis of (112) peak for G0, G3 and G6 thin films.

| XRD peaks | (112) | (220) | (312) | FWHM of (112) |
|-----------|-------|-------|-------|---------------|
| G0 | 26.67 | 44.22 | 52.34 | 0.284 |
| G3 | 26.70 | 44.35 | 52.48 | 0.232 |
| G6 | | | | 0.225 |

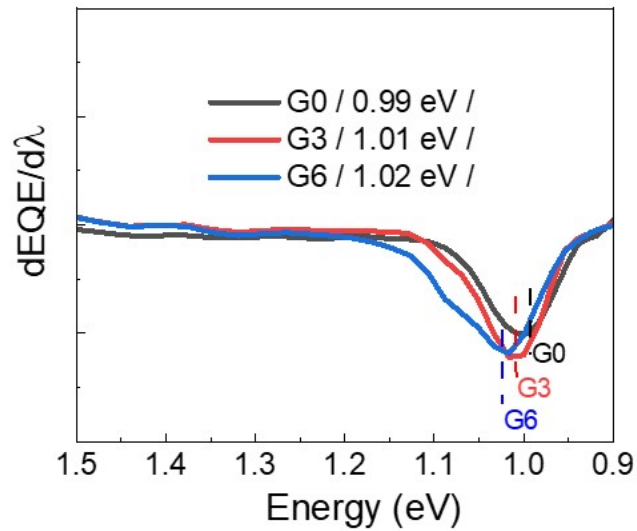


Fig. S3. Optical bandgap (E_g) extraction of G0, G3 and G6 devices.

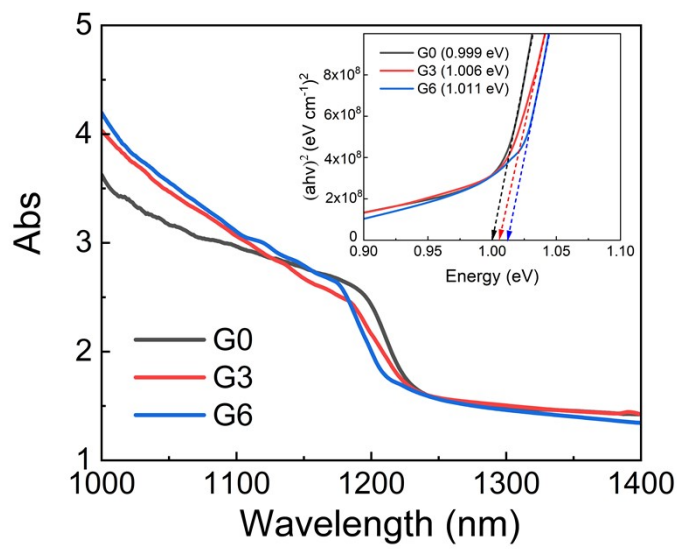


Fig. S4. NIR absorption spectra of G0, G3, and G6 thin films deposited on bare SLG substrates. The inset shows the Tauc ($(\alpha h\nu)^2$ vs. $h\nu$) analysis.

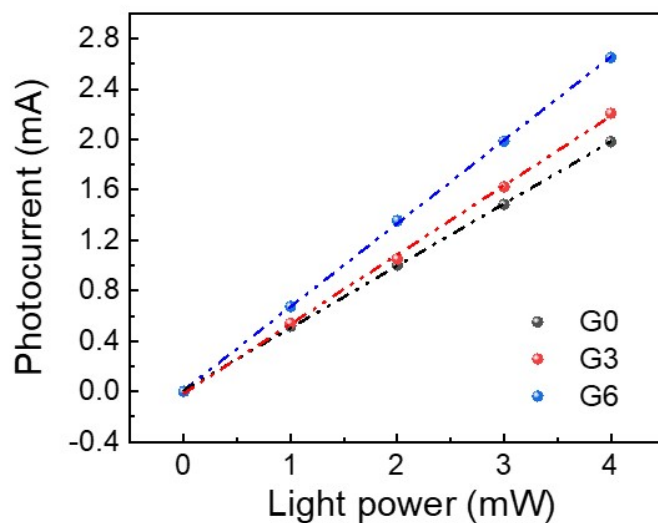


Fig. S5. Illumination light power vs. photo-current for G0, G3 and G6 devices at 0 V bias.

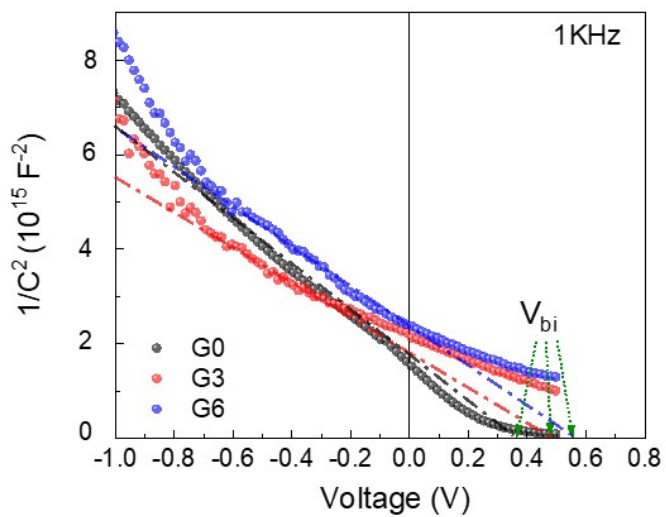


Fig. S6. Mott-Schottky plot for G0, G3 and G6 devices.

References

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